OXFORD PLASMAPRO NGP1000 PECVD SYSTEM consisting of:

- Model: Oxford PlasmaPro NGP1000 PECVD
- Load Locked Chamber
- System PC, Keyboard, Mouse
- Windows 7 w/ PC4500 Control Software
- X20 PLC
- 490mm Diameter Aluminum Lower Electrode
- Capable of running up 450mm wafers
- Up to 400 degrees Celcius
- Chamber Heating Kit (Heats Chamber Sidewalls to Minimize Process Deposition)
- Dual Frequency RF with Pulsing for Film Stress Control
- 600W 13.56Mhz HF RF Generator
- 600W 100khz LF RF Generator
- Gas-Shock assisted Chamber Lift Mechanism
- Adixen ADS602P Dry Pump for Process Chamber
- Load Lock vacuum pump
- Operations Manual and Documentation
- Fully Refurbished to excellent condition (see below details)
- Vintage 2012

X20 External Gas Box with up to 12 Gas Lines. Currently Configured for:

- He
- CF4
- N2
- N20
- NH3
- SiH4-N2

OXFORD REFURBISHMENT PROCESS consists of:

- Chamber disassembled for refurbishment.
- Chamber received full wet clean.
- Chamber o-rings and seals are replaced with brand new.
- Electrostatic Chuck (ESC) sent out for refurbishment (if applicable)
- All MFCs rebuilt and calibrated professionally.
- All corrosive gas lines replaced with brand new.
- All Non-corrosive gas lines purged.
- Vacuum pumps professionally rebuilt.
- Turbo pump professionally rebuilt.
- Chillers serviced and fully tested.
- All wiring/wire harnesses are checked, repaired or replaced if needed.
- All liquid and air lines, tubing and fittings checked and replaced if necessary.
- Major components disassembled for checkout, servicing, cleaning, and lubricating. Parts are repaired or replaced as needed.
- Checkout of all electronic and mechanical parts.
- Machine covers are cleaned, polished or replaced as needed.
- Post-refurbishment system leak and RF calibration checks, with documentation provided to customer.
- System cycle and repeatability testing completed prior to cover replacement and wipe down.
- System components carefully packed, labeled, and professionally crated.